

REMARKS

Applicants respectfully request reconsideration of this application as amended. Claims 1-5, 8, and 28-38 are pending in the application. Claims 1-5, 8, 28 and 30-34 are allowed. Claims 29 and 35 have been amended. No new claims have been added. No claims have been canceled. No new matter has been added.

Claim Rejections - 35 U.S.C. § 112

The Examiner has rejected claims 29 and 35-38 under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

Claim 29 was amended to provide proper antecedent basis, thus overcoming the Examiner's rejection.

Claim 35 was rejected on the grounds that the system claim indicated only one nozzle for the dispense of photoresist, yet the claim also indicated additional drains and containers for additional types of resist. This is not a contradiction because the system has the feature of being able to switch the use of different types of photoresist when in the production of wafers without incurring significant down time, while still separately recovering the different photoresists. Therefore, even if the system is using only one type of photoresist at a time, the system is enabled to recover several types of photoresist when the system is switch to a different type of photoresist, without the need to incur substantial down time cleaning and retooling for the recovery of the new type of photoresist to be used. Claim 35 was amended to more particularly point out and distinctly claim the above features and distinctions.

Claim 35 was also rejected on the grounds that the Examiner was uncertain as to whether the recovery containers were actually part of the system being claimed. Claim 35 was amended to remove the questionable language. Applicants assert that claim 35, as amended, overcomes the Examiner's rejections.

Applicant, accordingly, respectfully requests withdrawal of the rejection of claims 29 and 35-38 under 35 U.S.C. 112, second paragraph.

Claim Rejections - 35 U.S.C. § 102

The Examiner has rejected claims 35 and 36 under 35 USC §102(b), as being anticipated by Yamauchi et al. (PAPUS2002/0112662) hereinafter “*Yamauchi*”. In light of the amendment, the Examiner’s rejections have become moot. Nonetheless, the following remarks regarding the Examiner’s rejections and the amended claims may be helpful to expedite prosecution.

Claim 35 relates to a system for photoresist recovery comprising: a nozzle to dispense a photoresist; a bowl having an interior region and an interior surface; a wafer platform disposed within the interior region of the bowl; a wafer spindle coupled to the wafer platform, the wafer spindle to spin the wafer platform to propel an excess amount of a photoresist deposited upon a wafer placed upon the wafer platform to the interior surface of the bowl; a photoresist recovery container; a perimeter drain formed within the bowl such that the excess amount of photoresist propelled from the wafer proceeds through the perimeter drain to the photoresist recovery container; a waste drain formed within the bowl; and one or more **additional perimeter drains** formed within the bowl to enable the **separate** recovery of one or more **additional types of photoresists**, which enables the system to **change photoresist types** while in production, thus **reducing down time** for photoresist **changing** operations.

In contrast, Yamauchi fails to disclose or suggest one or more **additional perimeter drains** formed within the bowl to enable the **separate** recovery of one or more **additional types of photoresists**, which enables the system to **change photoresist types** while in production, thus **reducing down time** for photoresist **changing** operations.

In view of the above remarks, a specific discussion of dependent claim 36 is considered to be unnecessary. Therefore, Applicants' silence regarding any dependent claim is not to be interpreted as agreement with, or acquiescence to, the rejection of such claim or as waiving any argument regarding that claim.

Applicant, accordingly, respectfully requests withdrawal of the rejection of claims 35 and 36 under 35 USC §102(b), as being anticipated by *Yamauchi*.

Claim Rejections - 35 U.S.C. § 103

The Examiner has rejected claim 37 under 35 U.S.C. 103(a) as being unpatentable over *Yamuchi* in view of *Yamasaka* (U.S. 5,997,653) hereinafter "*Yamasaka*". In light of the amendment, the Examiner's rejections have become moot. Nonetheless, the following remarks regarding the Examiner's rejections and the amended claims may be helpful to expedite prosecution.

Yamasaka is introduced to suggest the feature of the bowl being adjustable relative to the wafer platform. However, *Yamasaka* also fails to disclose or suggest one or more **additional perimeter drains** formed within the bowl to enable the **separate** recovery of one or more **additional types of photoresists**, which enables the system to **change photoresist types** while in production, thus **reducing down time** for photoresist **changing** operations. Therefore, *Yamasaka* fails to remedy the deficiencies in *Yamuchi*. Further, Applicants assert that independent claim 35, as amended and in light of the above remarks, has overcome the prior art of record, and thus dependent claim 37 should also have overcome the prior art of record.

Applicant, accordingly, respectfully requests withdrawal of the rejection of claim 37 under 35 USC §103(a), as being unpatentable over *Yamuchi* in view of *Yamasaka*.

CONCLUSION

For the foregoing reasons, the present application is believed to be in condition for allowance, and such action is earnestly requested.

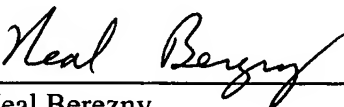
Pursuant to 37 C.F.R. 1.136(a)(3), applicant(s) hereby request and authorize the U.S. Patent and Trademark Office to (1) treat any concurrent or future reply that requires a petition for extension of time as incorporating a petition for extension of time for the appropriate length of time and (2) charge all required fees, including extension of time fees and fees under 37 C.F.R. 1.16 and 1.17, to Deposit Account No. 02-2666.

If there are any additional charges, please charge Deposit Account No. 02-2666.

Respectfully submitted,

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